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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application: Furukawa, et al

Group Art Unit: 2823

Serial No.: 09/599,783

Examiner: Julio J. Maldonado

Filed: 06/22/2000

Title: Method For Etching A Semiconductor  
Substrate Using Germanium Hard MaskENTERED  
OSmails-logu  
2/13/03Assistant Commissioner of Patents  
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OCT 25 2002RESPONSE TO FINAL REJECTION

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